

The Norwegian Research Centre
for Solar Cell Technology



Norwegian University of
Science and Technology

Challenges in GD-MS analysis of PV silicon materials

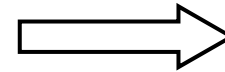
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EW-GDS

3rd-4th September 2012

Why do we need to measure impurities in PV silicon?

Silicon value chain
Role of impurities in solar cell silicon



Quantitative measurements ?

Raw Materials

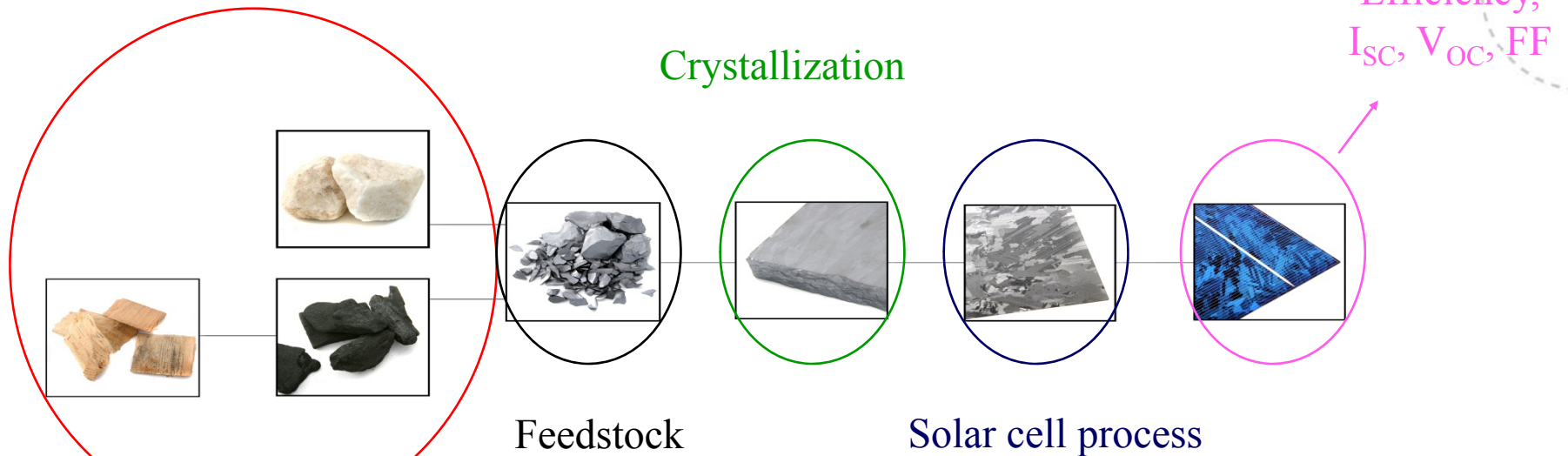
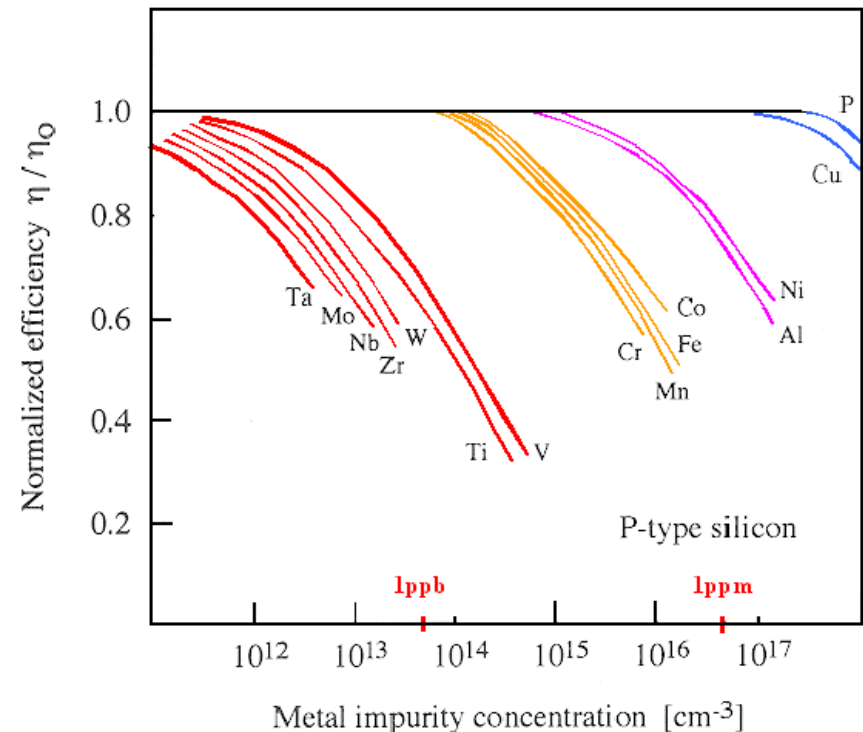
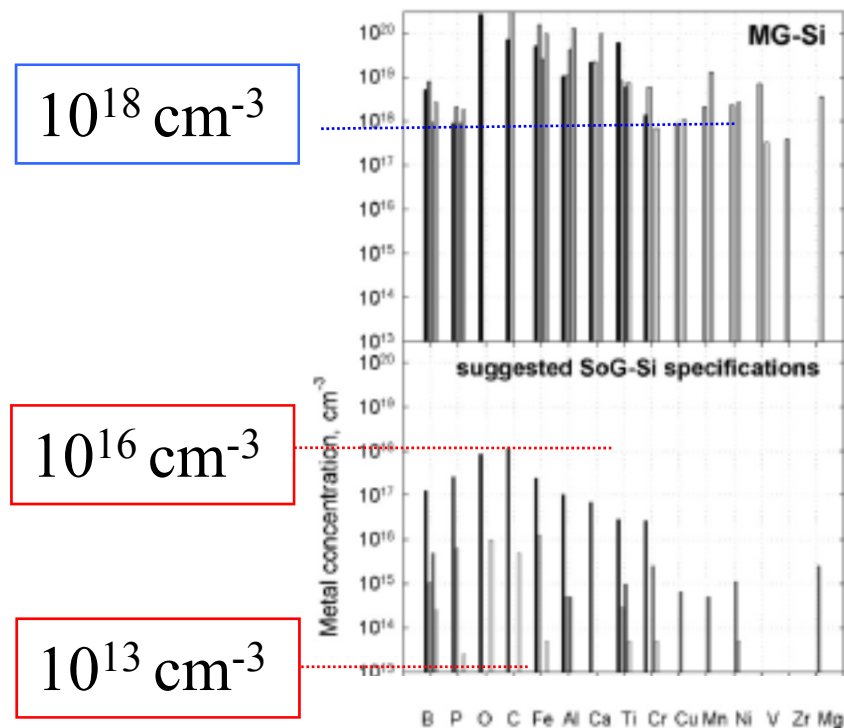


Photo: Melinda Gaal

Why do we need to measure impurities in PV silicon?



Istratov et al., Mat Sc Eng B (2006)

Davis et al. (1980), IEEE Transactions

Outline

- ❑ Trace element analysis in PV silicon
 - Occurrence in the matrix
 - Quantification of trace elements

- ❑ Applications of GD-MS for PV silicon:
 - Concentration of doping elements
 - Concentration of metal impurities

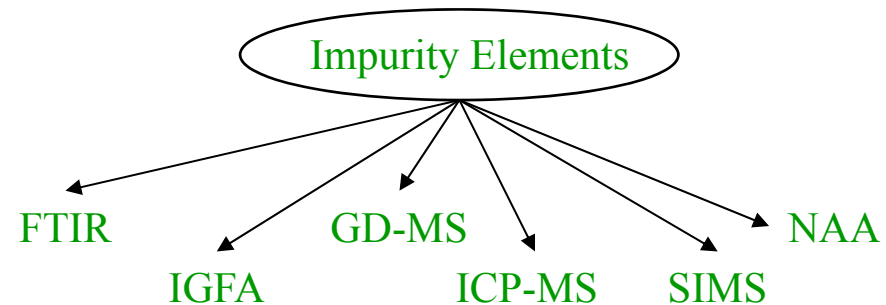
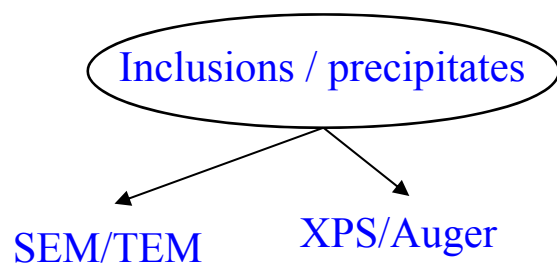
- ❑ Summary

Silicon for photovoltaics

- ❑ Si is a **semiconductor** material \Leftrightarrow the concentration of doping elements influences the possibility to perform GD-MS analyses
- ❑ Typical concentrations of doping elements (p-type solar cells) are in the range **110 – 300 ppba** \Leftrightarrow resistivity in the range 1 – 2.5 Ω cm

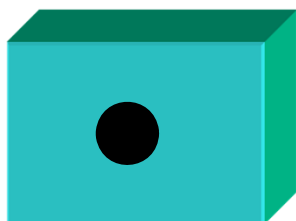
Analytical methods for trace elements analysis in PV silicon

- Impurities are present in Si for photovoltaics in 2 states:
 - Dissolved into the Si matrix: O_i , C_s , Fe_i , ...
 - As precipitates: metal-based, Si_3N_4 , SiC ...
- Impurities can be affected by macro- and micro-segregation \Leftrightarrow different techniques are available / suitable to measure the impurities

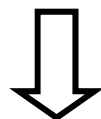


Experimental setup

Flat samples - sample size:
max. \varnothing 70 mm, 40 mm height
min. \varnothing 20 mm



Analysed area: $\varnothing \sim 8\text{mm}$



Bulk measurement, average over a wide area



Thermo ELEMENT GD

Sputtering rate = 20 nm/sec

Quantification of trace elements

The quantification of the concentration of the elements is done according to:

$$C_X = \frac{(I_X)}{(I_M)} \cdot \frac{(A_M)}{(A_X)} \cdot \text{RSF}$$

C_X : concentration of element (isotope)

C_M : concentration of matrix (Si^{28})

I_X : intensity (cps) of element

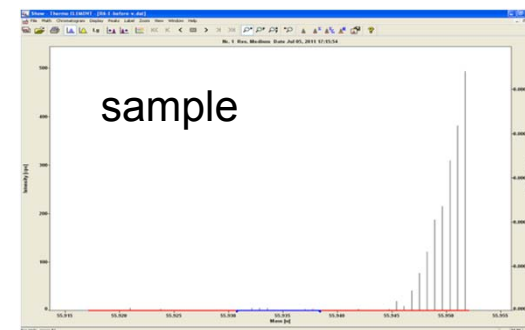
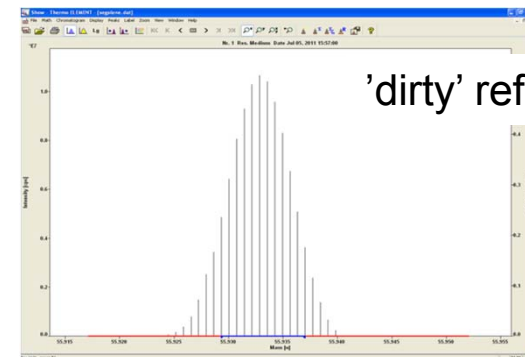
I_M : intensity (cps) of matrix

A_X : abundance of element (isotope)

A_M : abundance of matrix (Si^{28})

RSF: relative sensitivity factor (element-specific)

Ion Beam Ratio
(IBR) = I_X / I_{Si}



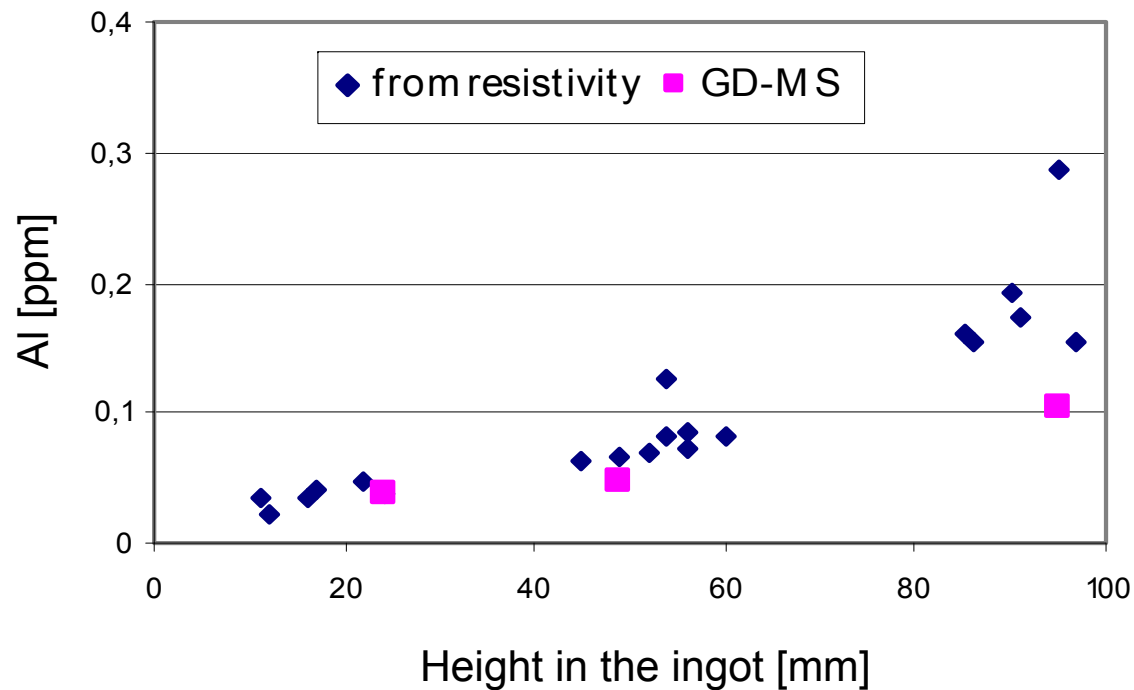
Applications of GD-MS for PV silicon materials

- ❑ Concentration of doping elements:
 - Indirect measurement of resistivity
 - Comparison with direct measurement of resistivity

- ❑ Concentration of metal impurities:
 - Important to understand their effect on the electronic properties of Si

Applications - Dopant concentration

mc-Si with Al doping, p-type semiconductor

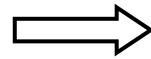


ASTM F723-99

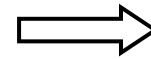
$$N_{\text{acceptor}} = \frac{c_1}{\rho} + \frac{c_2}{f(\rho)}$$

Applications - Dopant concentration from Fe-acceptor pairing

Minority carrier lifetime before and after light soaking (Fe-B pairs dissociate)

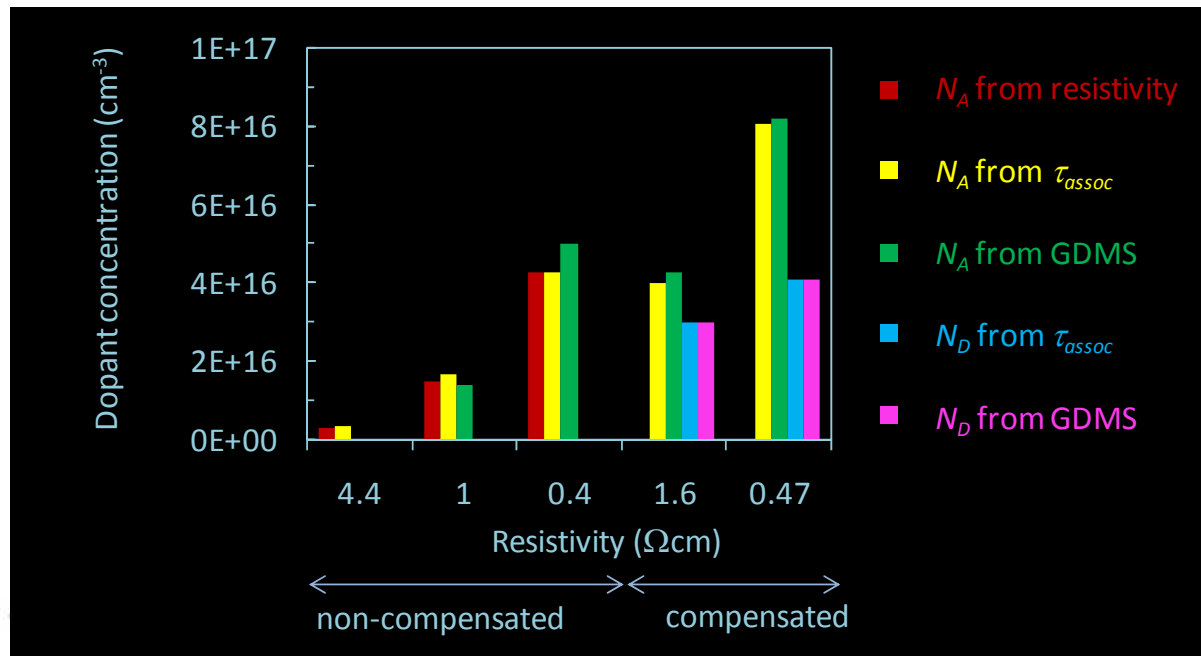


calculate
B, N_A and P, N_D



comparison

B and P by GDMS

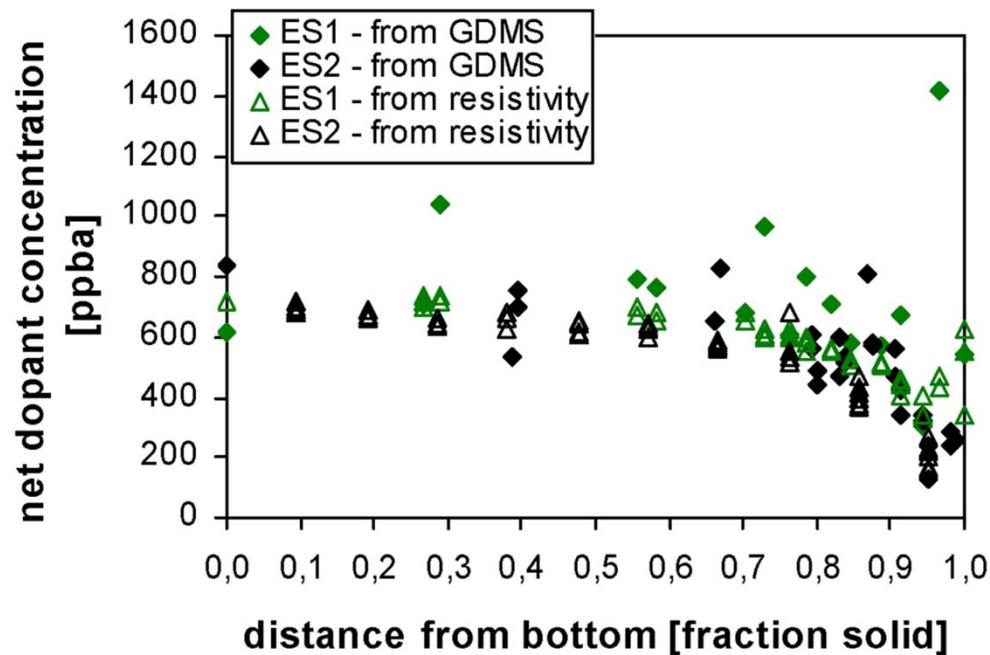


Macdonald et al.,
EUPVSEC (2008)

Applications - Net doping in compensated silicon

Compensation \leftrightarrow high content of acceptor (B) and donor (P) species

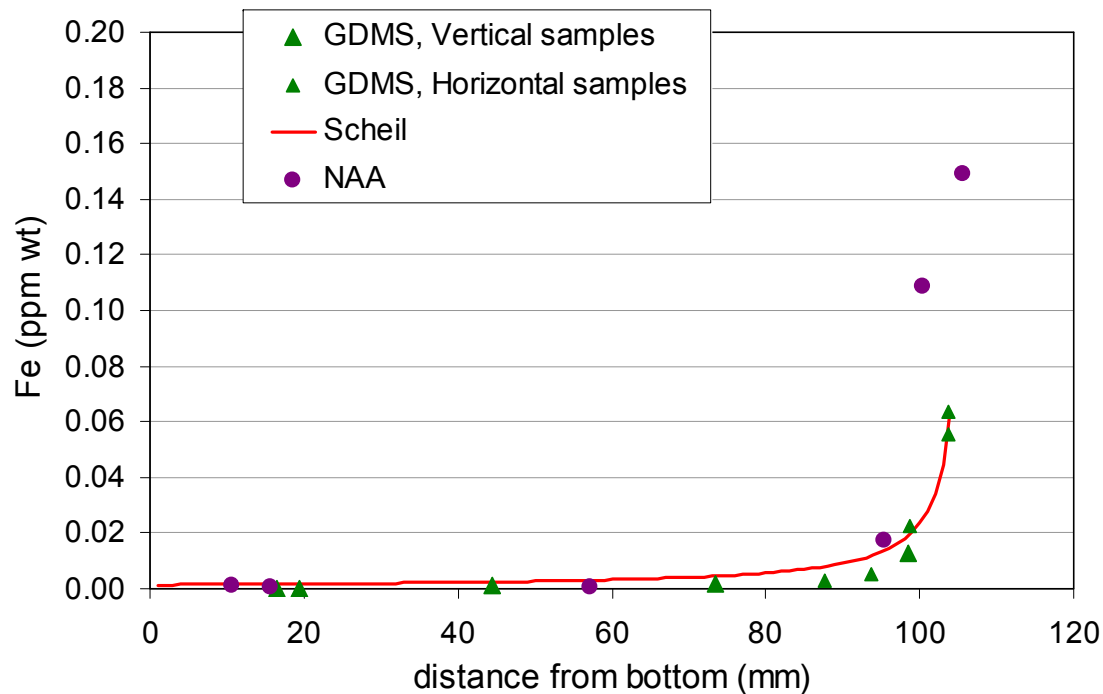
conversion equation from ASTM F723-99 for p- or n- type may be applied to the net doping



developed method by GDMS

$$N_{\text{NET}} = (B + A1) - (P)$$

Applications - Fe addition



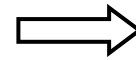
□ 50 ppmw Fe were added to the Si melt

□ Given the low segregation coefficient ($C_{sol} / C_{liq} \approx 10^{-5}$), most of the Fe segregates towards the top of the ingot (last to solidify) ⇔ non-homogeneous distribution

Applications - Study of grain boundaries

Metal impurities in PV Si can form precipitates:

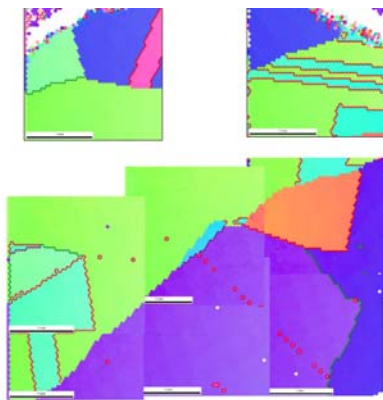
- they are detrimental for electronic properties
- they usually segregate at grain boundaries



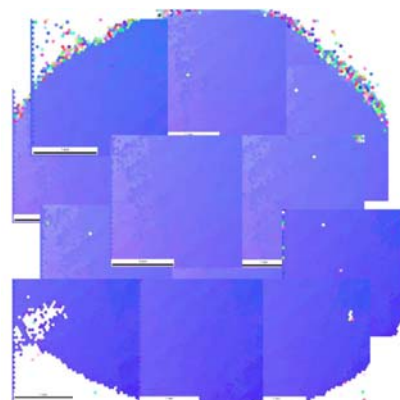
Is there any difference due to sample microstructure (i.e. random grain boundary, single grain, twin boundary)?

Selected areas:

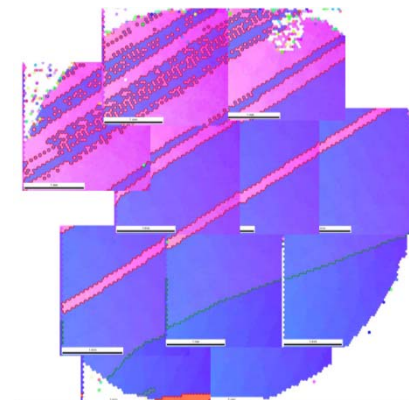
- SG1: single grain, area 1
- GB1: (random) grain boundary, area 1
- TB1: twin boundary, area 1



GB1



SG1

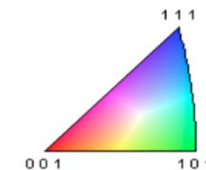


TB1



Color Coded Map Type: Inverse Pole Figure [001]

Silicon



Applications - Study of grain boundaries (continue)

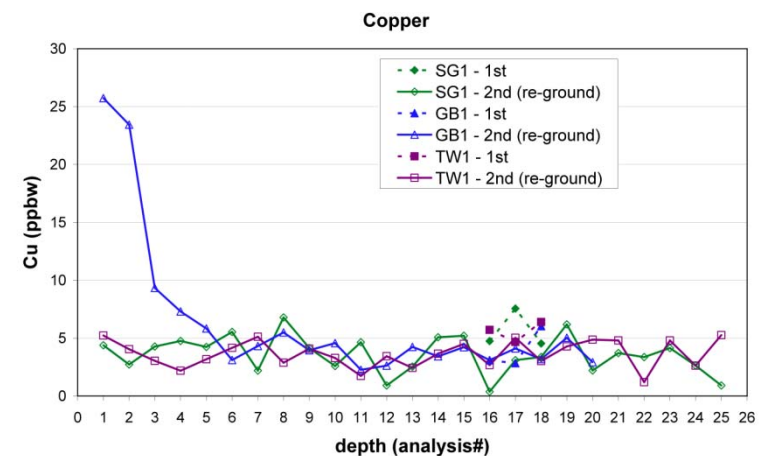
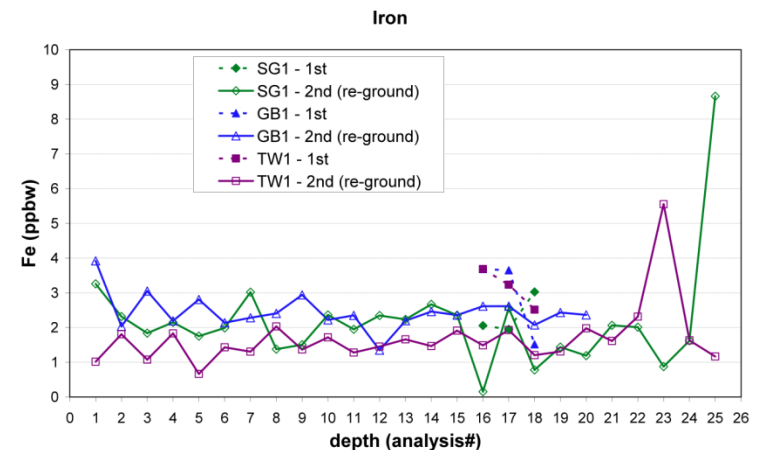
Selected impurities in mc-Si: Fe and Cu

Selected areas:

- SG1: single grain, area 1
- GB1: (random) grain boundary, area 1
- TB1: twin boundary, area 1

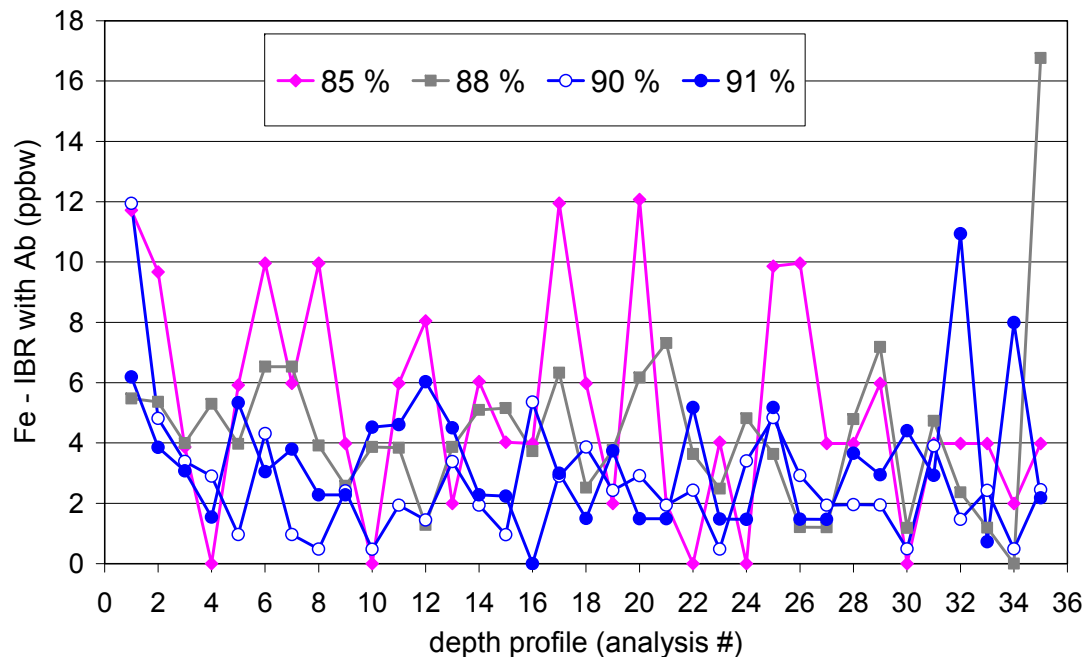
➤ No clear evidence of precipitates ⇔ too low concentrations ?

No pre-sputtering!



Applications - Depth profiling and investigation of precipitates

□ p-type Si ingot, with 50 ppmw ($1.25 \times 10^{18} \text{ cm}^{-3}$) Fe and 128 ppbw ($1.66 \times 10^{16} \text{ cm}^{-3}$) B added to the melt (prior to casting)



No pre-sputtering!

Applications - Depth profiling and investigation of precipitates

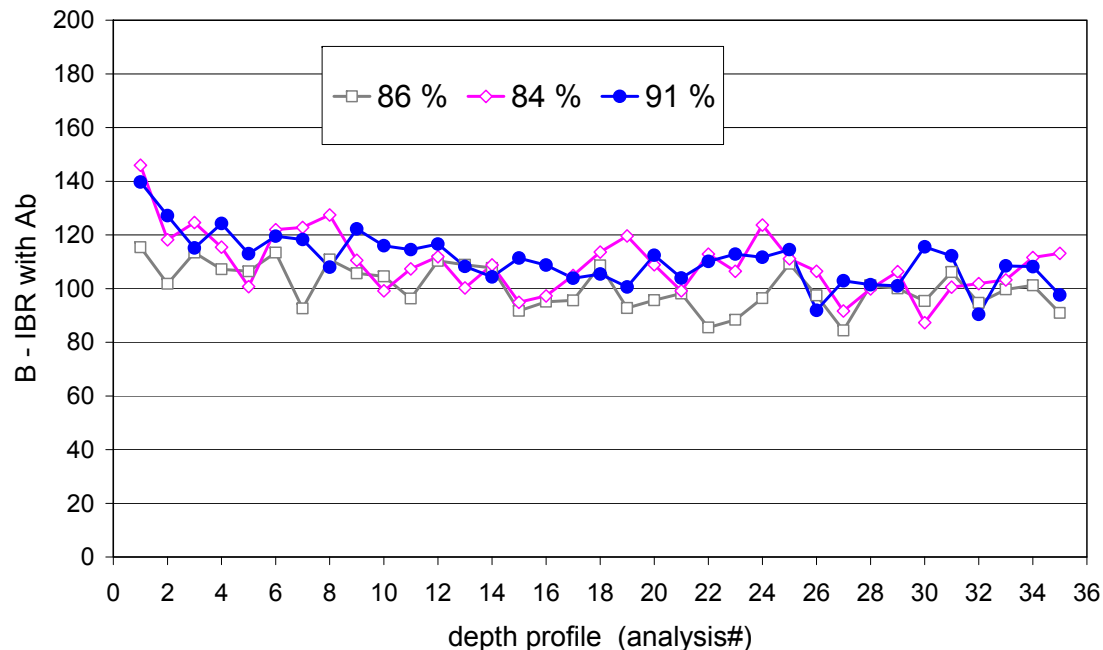
□ p-type Si ingot, with 50 ppmw ($1.25 \times 10^{18} \text{ cm}^{-3}$) Fe and 128 ppbw ($1.66 \times 10^{16} \text{ cm}^{-3}$) B added to the melt (prior to casting)

Sample	Si28 (cps)		Fe56 (ppbw)	
	AVG	STDEV	AVG	STDEV
85%	1.01×10^9	9.64×10^6	5.2	3.6
88%	1.61×10^9	6.77×10^7	4.3	2.9
90%	4.15×10^9	2.56×10^7	2.6	2.1
91%	2.69×10^9	5.13×10^7	3.4	2.2

- Non-homogeneous Fe concentration
- Averaging over several repeated analyses
- Low Fe levels, although the impact on electronic properties is strong at these low concentrations

Applications - Depth profiling and investigation of precipitates

□ p-type Si ingot, with 50 ppmw ($1.25 \times 10^{18} \text{ cm}^{-3}$) Fe and 128 ppbw ($1.66 \times 10^{16} \text{ cm}^{-3}$) B added to the melt (prior to casting)



No pre-sputtering!

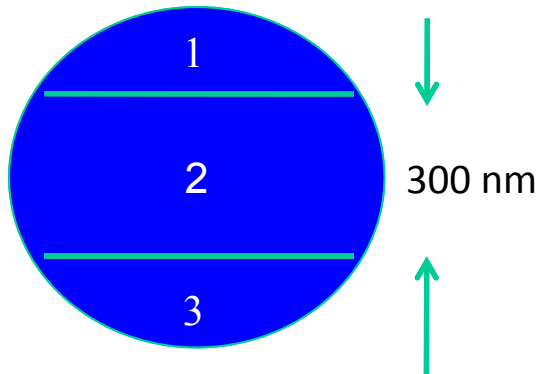
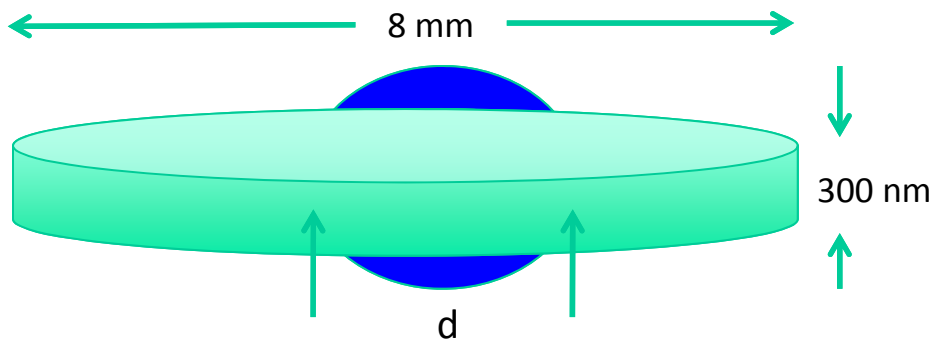
Applications - Depth profiling and investigation of precipitates

□ p-type Si ingot, with 50 ppmw ($1.25 \times 10^{18} \text{ cm}^{-3}$) Fe and 128 ppbw ($1.66 \times 10^{16} \text{ cm}^{-3}$) B added to the melt (prior to casting)

Sample	Si28 (cps)		B11 (ppbw)	
	AVG	STDEV	AVG	STDEV
84%	4.57×10^9	4.93×10^7	109	11.6
86%	4.28×10^9	2.72×10^8	101	8.2
91%	5.51×10^9	6.48×10^7	111	10.0

- Homogeneous B concentration
- Compared to Fe, lower number of analyses required
- Important to have a precise quantification due to the B impact on the conductivity

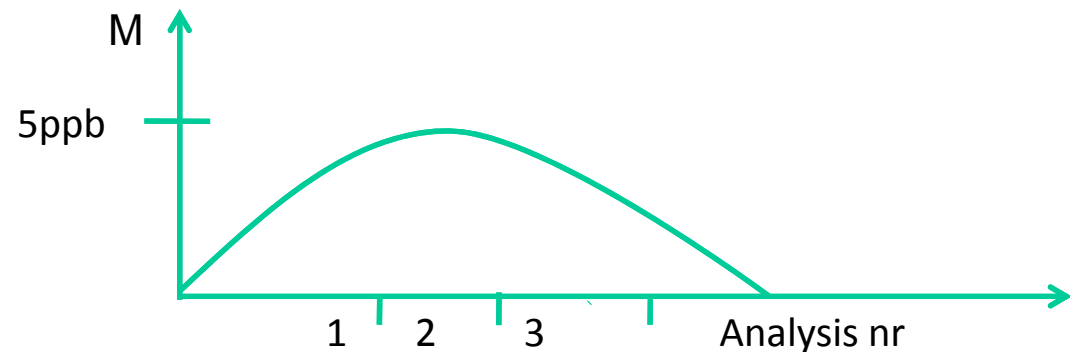
Challenges in the study of GB and dislocations



Conclusion:

❑ 300 nm particle with 0.5% M \Leftrightarrow 0.5×10^{-9} , below LoD!

❑ Estimation of the size of precipitates for detection \Leftrightarrow to give 5 ppb M, a single particle should have $\varnothing = 660$ nm!



Concluding remarks

- GDMS can provide **reproducible** measurements of doping and trace elements in silicon for photovoltaics, with **precise quantification** down to **low-ppb** levels
- Applications for PV Si - examples:
 - Concentration of **doping elements**: doping, net doping
 - Concentration of **metallic impurities**: segregation profile, relation to micro- and macro-segregation
- Further work: tuning of measurements for precipitates analysis

